

Challenges and Solutions in 3DIC Extractions



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Agenda

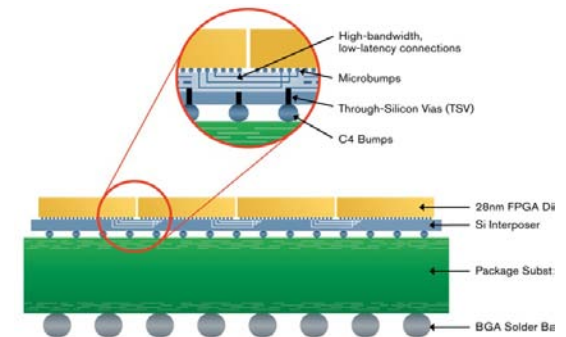
- I. Status of 3DIC integration
- II. Die stacking configurations
- III. Stack verification and extraction methodology
- IV. New challenges in extraction and future work
- V. Conclusion

Status of TSV based 3D-IC

- 3D ICs are real. Lot of activities and announcements
- Driven by the customer demands for more functionality, larger bandwidth, low power, smaller size;
- Inability of 2D SoC to respond to the customer demands in cost effective and timely manner.
- Problems with further scaling and SoC are becoming more obvious
 - ROI shrinks with every new technology node
 - Fab cost, process R&D, mask set, Chip Design, EDA,...
- There are still challenges in 3DIC but no technological show stoppers
- Various configurations -- 2.5 D (interposer based) and 3D
 - Interposers got into the center of attention due to the industry first stacked silicon (Xilinx Virtex FPGA)
- Will stay around long, but might not be sufficiently good for all applications

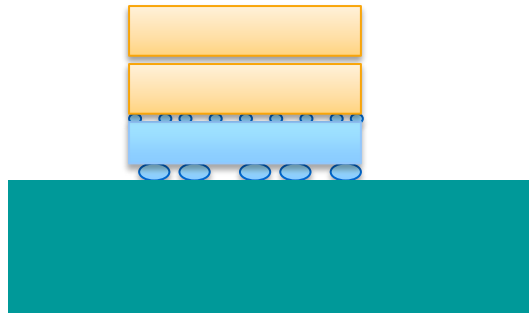
| Company | Interposers | | 3D with TSV | |
|-----------------|-------------|------|-------------|------|
| TSMC | 2H 2011 | [2] | 2012-2013 | [3] |
| UMC | | | 2H 2011 | [4] |
| GlobalFoundries | | | 2013 | [5] |
| IBM | 2011 | [6] | | |
| Samsung | | | 2012 | [7] |
| Elpida | | | 2H 2011 | [4] |
| Micron | | | 2012 | [8] |
| Nanya | | | 2011-2012 | [9] |
| ASE | 2012-2013 | [10] | | |
| STATSChipPAC | | | 2013 | [11] |
| Amkor | 2H 2011 | [3] | | |
| SPIL | 2011 | [12] | 2012 | [12] |
| Qualcomm | | | 2013 | [12] |
| Nokia | | | 2012-2013 | [12] |
| Xilinx | 2H 2011 | [2] | | |
| Dell | | | 2012 | [13] |

Source: P.Garrou, Micronews, Jan.2011.

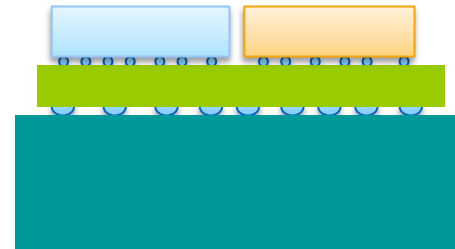


Source: www.xilinx.com/technology/roadmap/ssi-technology.htm

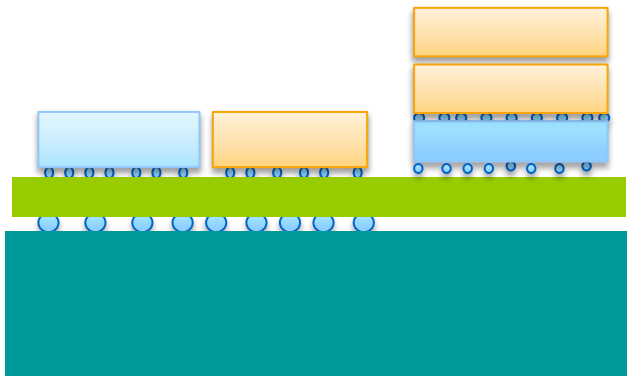
Some of the typical 3DIC configurations



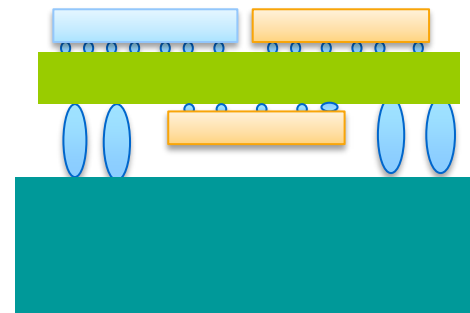
3D Memory on Logic
One or More DRAM die stacked directly on logic die



2.5D Side by side die stacked on a passive interposer that includes TSV's



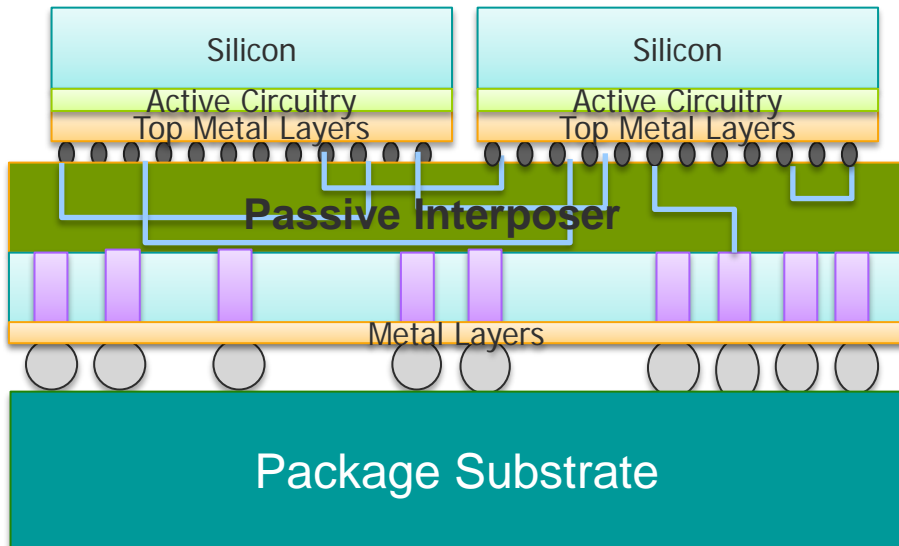
3D + Interposer
Mix of side by side and stacked implementations on an interposer



2.5D or 3D Interposer with top and bottom connection

2.5D vs. 3D configurations

2.5D Stacking, Interposer

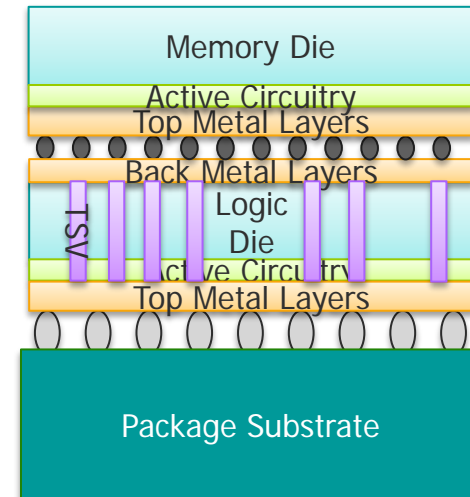


Advantage: No on-chip TSVs

Concern: Interposer size and cost

Applications: Not- Phone driven

3D Stacking, Die on Die



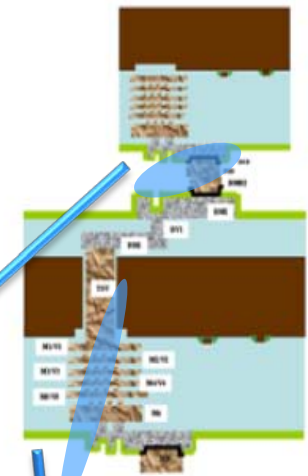
Advantage: Form factor, performance, power

Concern: TSV integration, thermal, stress

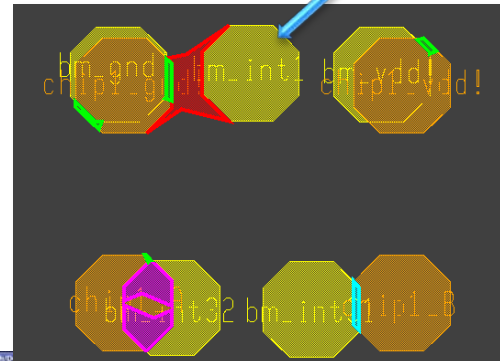
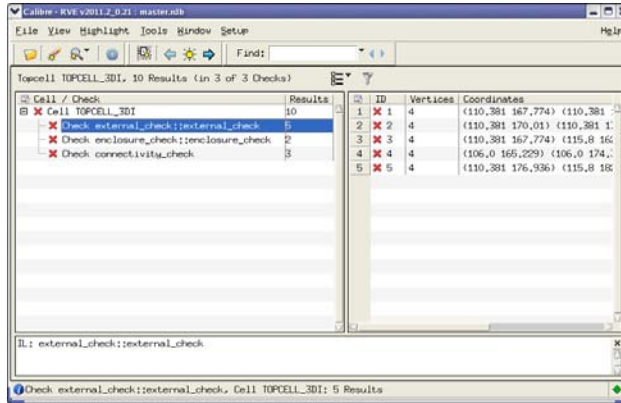
Applications : Mobile phone driven

3D-IC Physical Verification

- DRC: verify micro-bumps are physically aligned
- LVS: verify proper electrical connectivity through die interfaces



(b) AF-BF Bonding (2BM)

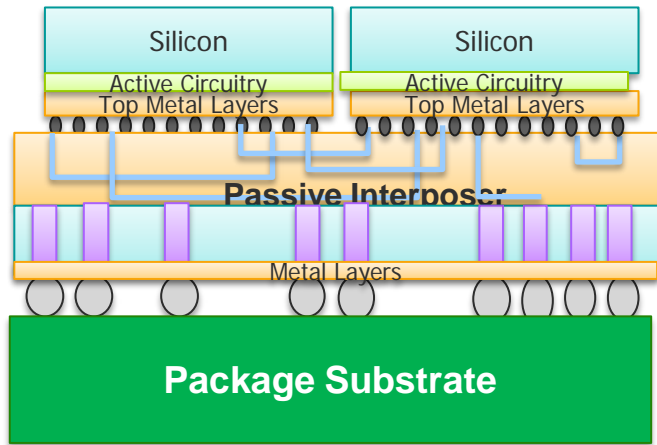


- PEX: Extracts parasitics of interconnect and BRDL
- Inserts provided TSV circuit into the netlists

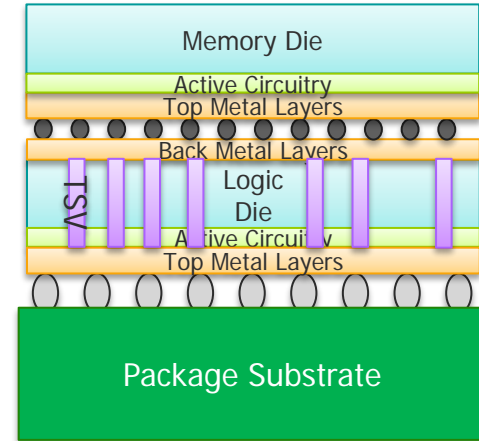
| No. | Layout Net | Source Net | R Count | C Total (F) | C+CC Total (F) |
|-----|------------|------------|---------|-------------|----------------|
| 11 | INT2_RIGHT | INT2_RIGHT | 9 | 3.92314E-15 | 3.92314E-15 |
| 12 | INT1_TOP | INT1_TOP | 21 | 6.75269E-15 | 6.75269E-15 |
| 13 | INT3_LEFT | INT3_LEFT | 10 | 3.76971E-15 | 3.76971E-15 |
| 14 | INT2 | INT2 | 10 | 5.08715E-15 | 5.08715E-15 |
| 15 | INT3_RIGHT | INT3_RIGHT | 9 | 4.55208E-15 | 4.55208E-15 |
| 16 | bm_vdd1 | BM_VDD1 | 5 | 4.55105E-14 | 4.55105E-14 |
| 17 | bm_int31 | INT2 | 5 | 6.97503E-14 | 6.97503E-14 |
| 18 | bm_int1 | INT1 | 3 | 5.84811E-14 | 5.84811E-14 |
| 19 | INT2 | INT2 | 1 | 2.84030E-14 | 2.84030E-14 |
| 20 | bm_gnd1 | BM_GND1 | 5 | 4.55105E-14 | 4.55105E-14 |
| 21 | bm_int32 | INT3 | 5 | 6.93562E-14 | 6.93562E-14 |

| Type | Count | Total | Layout Net | Source Net | Resistors: R (Ω F) |
|------|-------|-------------|------------|------------|--------------------|
| R | 3 | 5.84811E-14 | bm_int1 | INT1 | |
| | | | 1 | bm1 | 0.149125 |
| | | | 2 | bm1 | 0.0347198 |
| | | | 3 | bm2 | 0.00364558 |

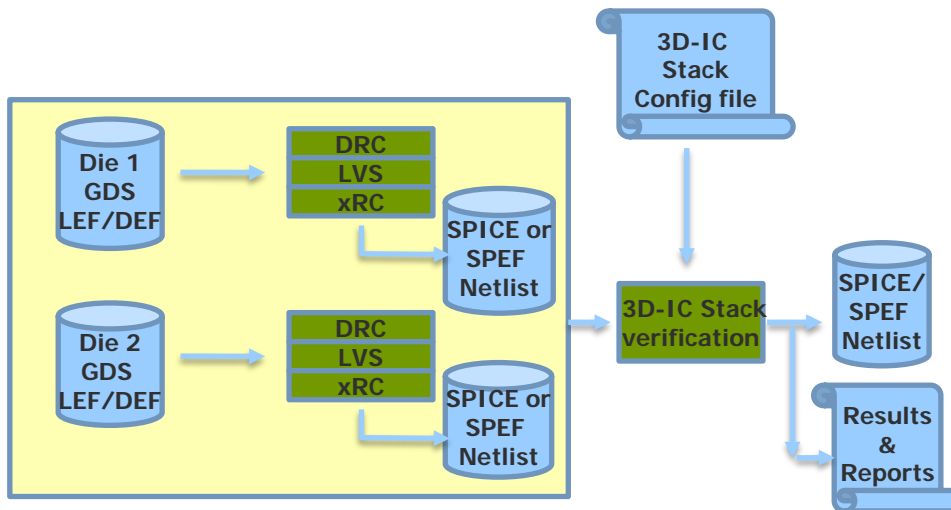
3D-IC Verification Flows



2.5D



3D



- Single net-list for double sided die (3D) including front metal parasitics, TSV and back metal parasitics stack including TSV and backside metal
- Separate Interposer netlist (2.5D)
- Combined netlist, if desired, for simulation across the dies in the stack

Verification Flows: Analog vs. Digital

Analog flow

Requires more accurate TSV model

Treat TSV as a LVS device or as a via

LVS device described by Spice sub-circuit

Generates HSPICE, ELDO netlist

Dynamic circuit simulation

Digital flow

Lower accuracy model requirements

Treat TSV as a via

Extraction tool generates R(C) model
Can be replaced by provided model

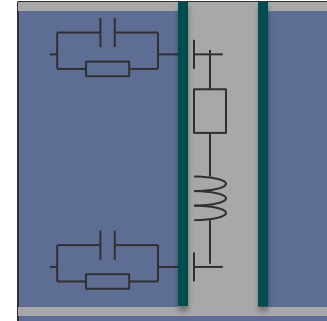
Generates SPEF or DSPF netlist

Static timing analysis

Issues in the existing verification solutions

- Present Solution

- TSV as LVS device or as a VIA
- Circuit for TSV provided
 - Typically obtained by S-parameter measurements and circuit parameter extraction
- Model of arbitrary complexity supported for TSV in simulation
- Double-sided die front and back metal parasitic extraction
- Sufficiently good for some applications (regular layout, no RDL, low density TSVs)



- Problems with the existing solutions

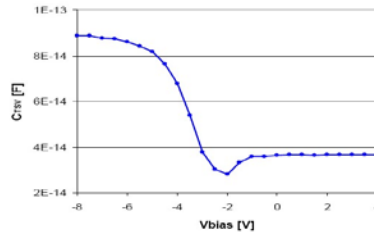
- Not adequate for high density, high frequency applications
- Problem with non-uniform environment around the TSVs
- Does not account for TSV interactions with other TSVs, interconnect, devices
- Does not consider inter-die interactions



Issues in Modeling of TSVs and their interactions

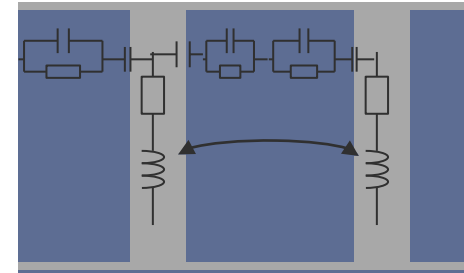
- TSD or TSV

- Nonlinear behavior



- Interactions between the TSVs

- Capacitive and Inductive couplings

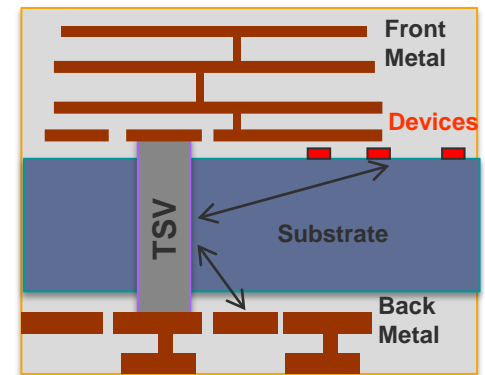


- Interaction between TSV and interconnect

- Interactions with RDL and metal lines

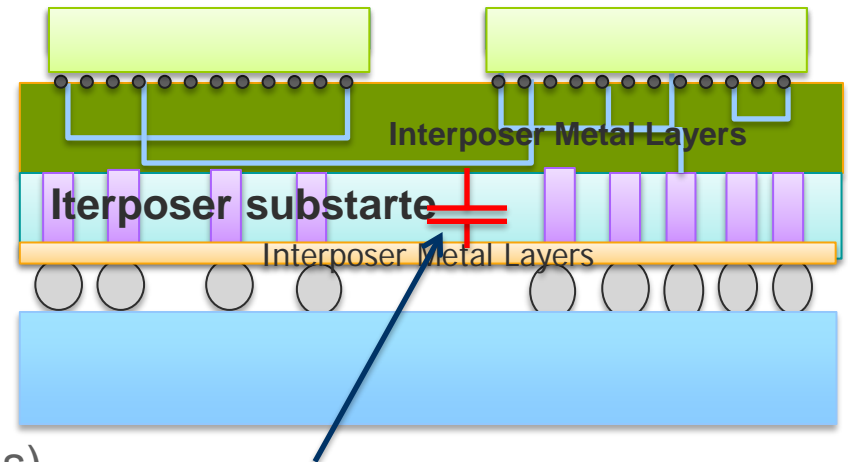
- Impact of TSVs on device performance

- Proper substrate description and modeling is needed



Interposer couplings

- Interposer metal coupling might be significant
- In 3D configurations substrate is grounded; Interposer substrate is floating
- Hard to take into account with rule based extraction due to semiconductor nature of the substrate and frequency dependence of couplings
- Substrate treated as
 - Dielectric (for higher frequencies)
 - Floating Metal (for lower frequencies)
- Not accurate for all frequencies of interest
- Field Solver based solution might be needed



In 2.5D Configurations
This coupling might need
to be modeled!?

Dies Interface modeling

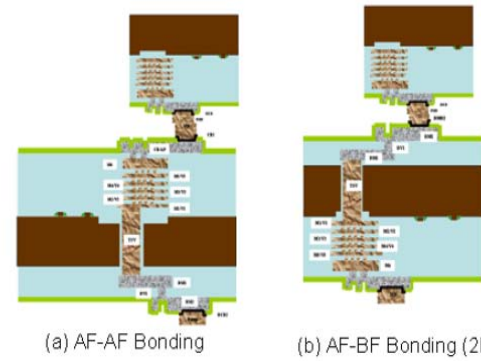
- Bump/Pillar bonding is common

- Bump/Pillar modeling, interactions and shielding

- Other bonding techniques

Typical for Monolithic 3DIC (3DIC Si Integration)

- Cu-Cu bonding
- Oxide bonding



Source: Qualcomm

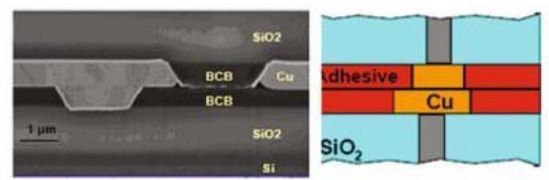
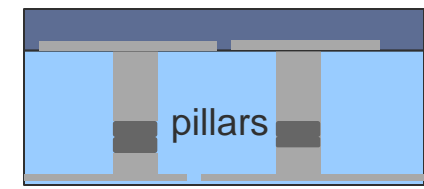
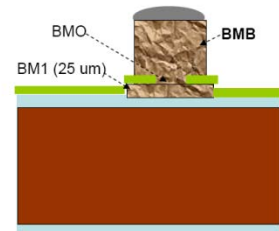
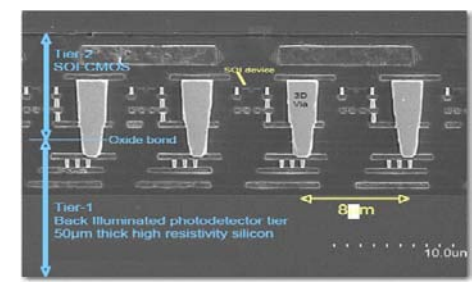


Fig. 1.35 A die-Stack using a combination of Cu-Cu and BCB adhesive bonding at RPI [14]

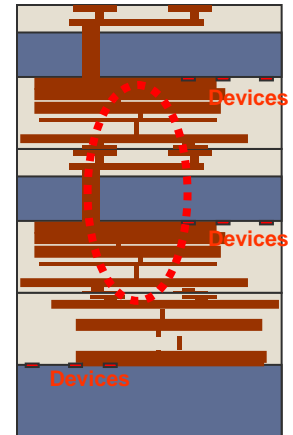
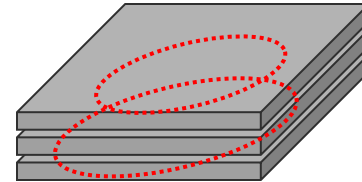
Source: RPI



Source: Lincoln Lab

Inter-die interactions

- Capacitive coupling might not be negligible between the dies, especially in Face-to-Face connection
- Magnetic coupling between the dies
 - The dies are getting closer together
 - Overlapping loops between the dies
- Full stack IR drop is needed
 - As number of TSVs is increasing, the interactions are becoming stronger, and IR drop analysis has to be done simultaneously for the entire stack
- The paths go across the dies and LVS, extraction and simulation have to go across the dies.



Alternative Modeling Approaches

■ Single TSV models

- Advantage
 - Easy to integrate into a flow ; Sufficient for present needs
- Challenges
 - Not adequate for high density, high frequency applications

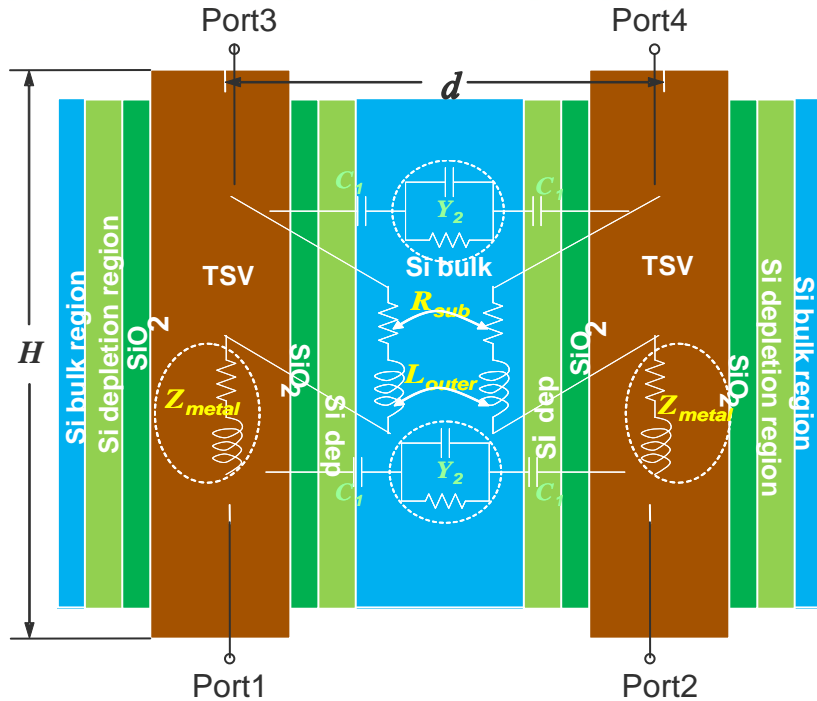
■ Compact models

- Advantage
 - Can account for some interactions; Faster than FS
- Challenges
 - Hard to account for all situations, to parameterize for all important variables

■ Field solver approach

- Advantage
 - Most accurate
- Challenges
 - Performance; Integration

TSV Modeling: Compact Model for a TSV Pair

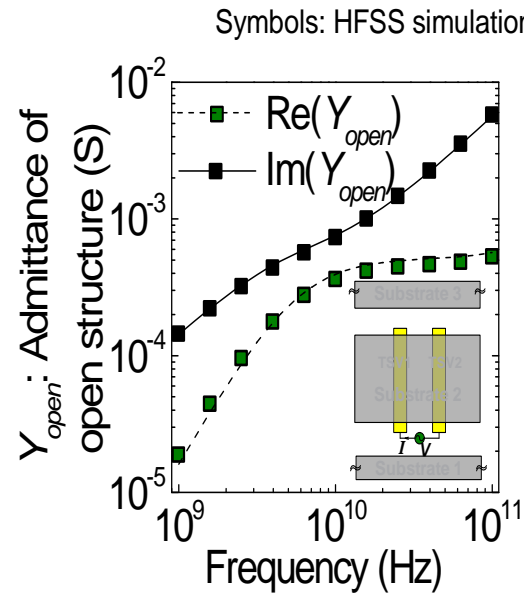


Compact RLGC Model accounts for

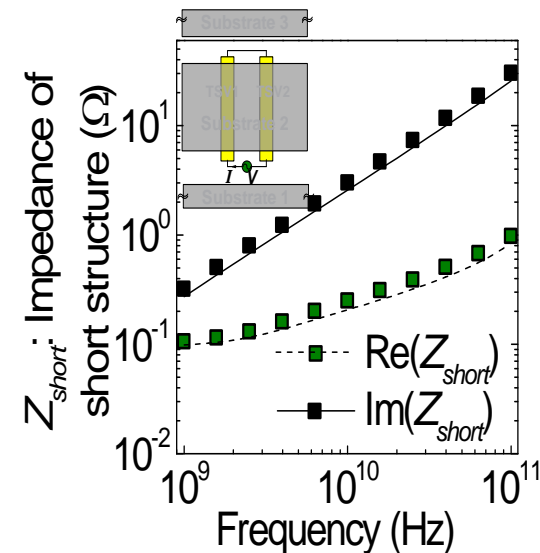
- Wide frequency range
- Skin effect
- Eddy currents in substrate
- MOS effect

Source: C. Xu, H. Li, R. Suaya, and K. Banerjee, "Compact AC Modeling and Analysis of Cu, W, and CNT Based Through-Silicon Vias (TSVs) in 3-D ICs," in /IEDM/Tech. Dig./, 2009, pp.521-524

Models-based results show good agreement with Field solver results (HFSS)

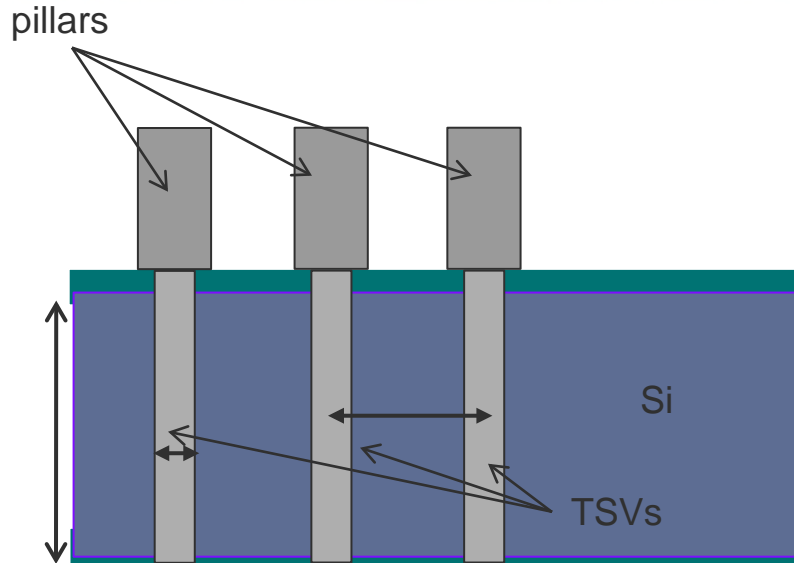


Open Structure



Short Structure

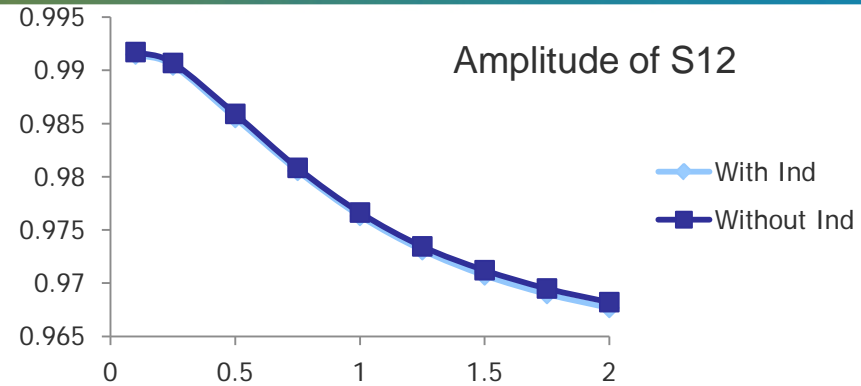
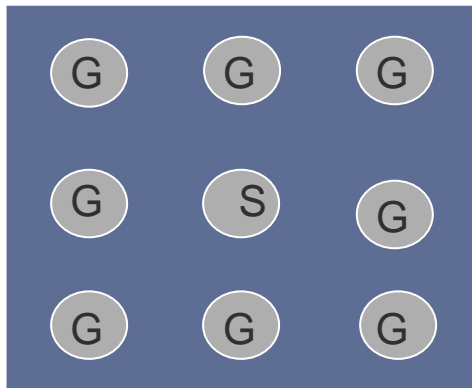
TSV Modeling: Fast Field Solver



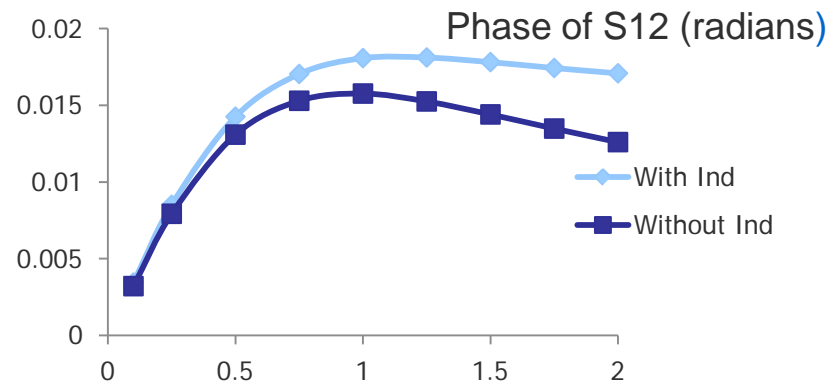
Two ports defined:

- Port 1: Signal Pillar to Ground Pillars
- Port 2: Signal TSV to Ground TSV
- Ground TSVs are shortened together

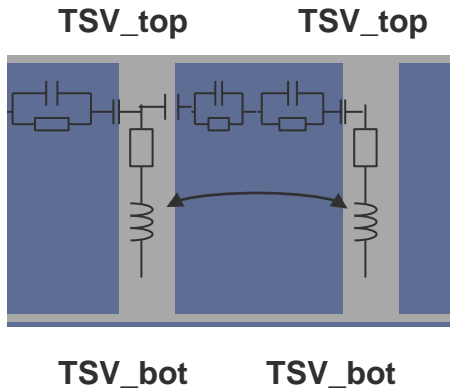
Top View



- Energy loss proportional to amplitude of S_{12}^2
 - ~ 6% @ 1.5GHz
- Inductance effect begins to show divergence at ~ 500MHz

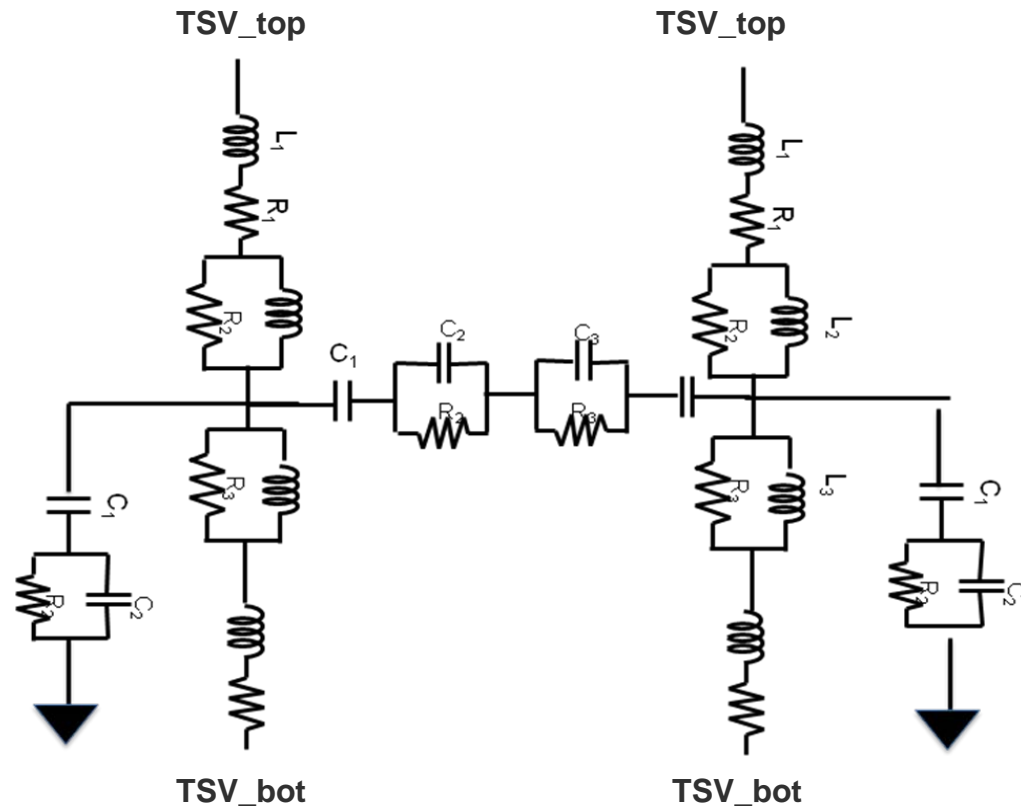


Fast Field Solver Output



Output:

Netlist of frequency-independent linear elements.
Values of those elements will be computed by fitting the frequency dependent results of the field solver



Conclusions

- Lot of challenges in design and verification of 3DICs, more in 3D than in 2.5D
- Present verification solutions inadequate for high TSV density and high frequency designs
- Challenges in parasitics extraction, not in DRC/LVS
- Determination of modeling/extraction accuracy needed to analyze TSV, intra and inter die interactions
- Need for modeling of TSVs and their interactions
- Fast field solver solution needed for accurate substrate effect modeling
- Efficient TSV model integration into the verification flows
- Analysis with inter die process variability

Source: Qualcomm

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